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JOURNAL OF APPLIED PHYSICS 120, 000000 (2016)

Propagation length of mid-infrared surface plasmon polaritons on gold: Impact of morphology change by thermal annealing

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We studied the propagation length of surface plasmon polaritons (SPPs) at the gold/air interface in the mid-infrared range. We showed that SPPs propagate for a distance of about or above 10 mm at a wavelength of $10.6 \,\mu m$, in good agreement with the value predicted from the dielectric constant of polycrystalline gold. We also demonstrated that a simple treatment of thermal annealing led to noticeable elongation of SPP propagation length, accompanied by increased grain size and decreased surface roughness. Quantitative evaluation of SPP propagation length, in correlation with material's morphology, is important in designing plasmonic devices and beneficial for understanding the mechanisms of SPP's losses that underlie electric-field enhancement. Published by AIP Publishing. [http://dx.doi.org/10.1063/1.4966934]

I. INTRODUCTION

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Plasmonics in the mid-infrared (IR) range has gained increasing attention^{1,2} because of possible applications to surface-enhanced spectroscopy,^{3,4} chemical/bio sensing,⁵ thermal radiation control, optoelectronic circuit, nonlinear light-matter interactions, etc. Surface plasmons (SPs), including surface plasmon polaritons (SPPs) and localized surface plasmons (LSPs), can be excited at mid-IR wavelengths on various materials.² Here, the behaviors of SPs significantly vary according to the material where they are excited.²

SPs on highly doped semiconductors that have plasma frequencies in the mid-IR range are closely bound to the material surface, exhibiting wavelength shortening and large Ohmic loss at mid-IR wavelengths. Therefore, these materials are suited for subwavelength confinement. In contrast, SPs on noble metals that have plasma frequencies in the visible range are weakly bound to the material surface, exhibiting subtle wavelength shortening and small Ohmic loss at mid-IR wavelengths. Therefore, noble metals are suited for applications where any of small loss, long propagation length, and large electric-field enhancement is required.^{2,10} Among noble metals, gold is an excellent plasmonic material because of its high metallic conductivity and superior chemical stability.

The propagation length of SPPs is an important physical quantity^{12,13} because it sets the available physical size of plasmonic devices in applications like sensors and optoelectronic circuits. It is also important as a direct measure of SPP's losses, which underlie the degree of electric-field enhancement achievable upon excitations of SPPs and LSPs. Electric-field enhancement plays key roles in many plasmonic applications.

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SPPs decay by radiative damping and non-radiative damping. Radiative damping occurs by coupling with (or scattering into) free-propagating light and other SPP states. Non-radiative damping originates from scattering of free electrons by electrons, phonons, defects, impurities, crystallite grain boundaries, etc. 14 Here, we note that non-radiative damping ends up with Joule heating and, therefore, is often termed as the Ohmic loss. 12 Both radiative and non-radiative damping rates depend on the microscopic structure of materials. Therefore, evaluation of the SPP propagation length, together with characterization of material's morphology, helps us understand the loss mechanisms of SPPs.

The earlier studies reported the propagation length of mid-IR SPPs on polycrystalline metal films of gold, 15-17 silver, ^{16,17} and copper. ^{18,19} The reported values were, however, inconsistent with each other, and it was difficult to get deeper insights since material's morphology was not characterized. Nowadays, it is possible to characterize the morphology by a variety of scanning probe microscopy techniques. In recent publications, the propagation length of SPPs on gold at visible wavelengths¹² and dielectric function of gold^{20,21} have been studied in correlation with the morphology observed by atomic force microscopy (AFM). There has been, however, no report on the propagation length of mid-IR SPPs on gold, with simultaneous characterization of morphology.

In this study, we experimentally measured the propagation length of SPPs at the gold/air interface at a mid-IR wavelength of 10.6 μ m and correlated it with the morphology of gold. Here, we characterized the morphology by AFM, scanning electron microscopy (SEM), and electron backscatter diffraction (EBSD). We showed that SPPs propagate for a distance of about or above 10 mm, in agreement with the

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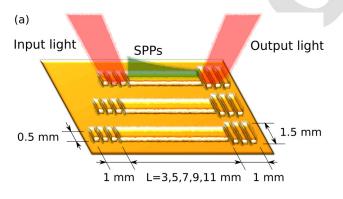
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value predicted from the dielectric constant of polycrystalline gold. Furthermore, we demonstrated that the SPP propagation length can be increased by a simple treatment of thermal annealing, accompanied by the increased grain size and suppressed surface roughness. In this study, we exploited surface-relief gratings as input/output couplers. Compared with the prism coupling, ^{18,19} the grating coupling does not suffer from contamination of collinear radiative components. 16,17 Compared with the edge coupling, 16,17 the grating coupling provides higher coupling efficiency and the resultant better signal-to-noise ratio.

II. DEVICE DESIGN AND FABRICATION

In order to measure the propagation length of SPPs, we designed a series of SPP waveguide devices. Each device consists of an input coupler, an SPP waveguide, and an output coupler. The input and output couplers are surface relief gratings made of gold. SPPs are excited at the input coupler from freely propagating light, propagate along the SPP waveguide, and are re-converted to freely propagating light at the output coupler, as illustrated in Fig. 1(a).

The input-output power ratio should be a product of light-SPP coupling efficiency, SPP propagation efficiency (or transmittance), and SPP-light coupling efficiency. Therefore, if the input/output coupling efficiencies are identical among all devices, we can deduce the propagation length (the distance that SPP power falls to 1/e of its initial value) by measuring the input-output power ratio for devices with different waveguide lengths. In the experiments, we assumed that the coupling efficiencies are identical among all devices and measured output optical power for each device, while keeping incident optical power constant.



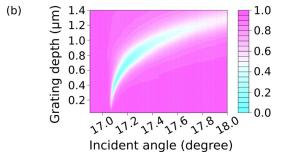


FIG. 1. (a) Schematic of the SPP waveguide devices. (b) Calculated reflection efficiency of a gold relief grating with a grating pitch of 15 μ m and a duty cycle of 0.5, as a function of incident angle and grating depth.

Freely propagating light and SPPs can be coupled to 114 each other by using a grating structure which satisfies the 115 condition²²

$$k_{\text{SPPgr}} = k_0 \sin \theta + \frac{2m\pi}{d},\tag{1}$$

where $k_{\rm SPPgr}$ and $k_0 = 2\pi/\lambda_0$ are the real parts of the complex 117 wavenumber of the SPP at the grating and that of light in 118 free space, respectively, λ_0 is the wavelength of light in free 119 space, θ is an incident angle, d is a grating pitch, and m is an 120 integer. Here, we note that $k_{\rm SPPgr}$ is close to the SPP wave- 121 number on a flat film in the case of shallow gratings.

Grating depth is known to be influential for the light- 123 SPP (SPP-light) coupling efficiency. 22,23 To find the opti- 124 mum grating depth for maximum coupling, we conducted 125 numerical simulations on reflection efficiencies of surface 126 relief gratings made of gold, by the rigorous coupled-wave 127 analysis.²⁴

Here, we assumed that each grating is made of polycrys- 129 talline gold and has a rectangular profile, a pitch of 15 μ m, 130 and a duty cycle of 0.5. Incident light was assumed to be a 131 plane monochromatic wave at a wavelength of $10.6 \,\mu\text{m}$. 132 Figure 1(b) shows the calculated energy reflection efficiency 133 as a function of incident angle and grating depth. The reflection efficiency reveals a dip at the grating depth of 135 $0.2-1.3 \,\mu \text{m}$ and at the incident angle of $17^{\circ}-18^{\circ}$. The energy 136 loss in reflection is due to conversion from freely propagat- 137 ing light to SPPs. Considering the possible beam conver- 138 gence of the incident light, we chose the grating depth of 139 $0.8 \,\mu \text{m}$ for efficient coupling. Our choice is close to the conclusion derived by Cleary et al. 23 that the optimum grating 141 depth of a rectangular grating was 10%-15% of the wave- 142 length in the mid-IR range.

Physical dimensions of our devices are presented in Fig. 144 1(a). The SPP waveguides have a common width of 0.5 mm 145 and varied lengths L of 3, 5, 7, 9, and 11 mm. The input (out- $\frac{146}{1}$ put) coupler is 1 mm in length and 0.5 mm (1.5 mm) in 147 width. Both the input and output couplers have rectangular 148 profiles with a grating pitch of 15 μ m and a duty cycle of 0.5. 149 The waveguides and the gratings were fabricated to have a 150 common height of 0.8 µm from a gold base layer.

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The devices were fabricated by means of electron beam 152 lithography, thermal evaporation, and lift-off process. A gold 153 base layer with a thickness of 200 nm was thermally evapo- 154 rated on a silica glass substrate with a 5-nm-thick chromium 155 adhesion layer, after the substrate was cleaned with acetone 156 and ethanol. Then, the electron-beam resist (OEBR-CAP112PM, Tokyo Ohka Kogyo Co., Ltd) was spin-coated 158 with a thickness of 1700 nm, exposed by electron beam, and 159 developed. Finally, gold with a thickness of 800 nm was 160 deposited on the developed resist, which was then lifted off 161 by acetone. During the evaporation process, the substrate was 162 not heated. The evaporation rate of gold was 0.4 nm/s, and the 163 pressure inside the vacuum chamber was less than 4 mPa.

III. EXPERIMENT

Figure 2 shows the schematic of our experimental setup. 166 A CO₂ laser (L3SL, Access Laser Company) was used as a 167

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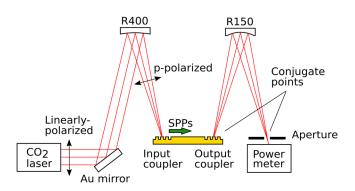


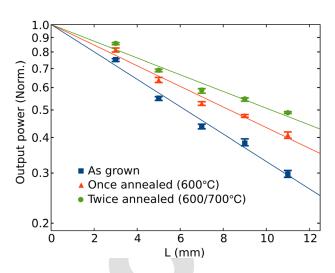
FIG. 2. Schematic of the experimental setup. R400 and R150 denote the spherical mirrors with curvature radii of 400 mm and 150 mm, respectively.

mid-IR light source generating linearly polarized light at a wavelength of 10.6 μm. Our SPP devices were attached to a rotational and 3D-translational stage. The p-polarized light (electric field lies within the plane of incidence) was incident onto the input coupler at the angle that fulfills Eq. (1) where m=1, being loosely focused by a spherical mirror with a curvature radius R of 400 mm. Here, the incident light converged with an angle of 1.3° to form the beam spot of 0.6 mm diameter at the sample position. This plane-like wavefront of the incident light and the homogeneous grating coupler should result in a SPP beam with plane-like wavefront. Because the focal depth of the excited SPP beam is about 10 mm, and because the SPPs are confined in the waveguides, we ignored the propagation loss due to diffraction. The output light was collected by a spherical mirror of $R = 150 \,\mathrm{mm}$ and a power meter. An aperture was placed at the conjugate point of the output coupler to avoid any stray light. Time-averaged optical power sent to the input coupler was controlled to be 60 mW by adjusting the duty ratio of RF power modulation in the CO₂ laser.

In order to modify the morphology of the gold film, the sample containing a series of waveguide devices was annealed twice with a hotplate in an argon atmosphere.²⁵ In the first annealing process, the sample was heated at 600°C for 20 min and gradually cooled down to room temperature on the hotplate. In the second annealing process, the sample was heated at 700 °C for 16 min and cooled down in the same way. The morphology was characterized by AFM (SPA-300, Seiko Instruments Inc.) in the tapping mode and by SEM/ EBSD (JSM-6510LV, JEOL Ltd.) with the acceleration voltage of 20 kV.

IV. RESULTS

Figure 3 shows the measured output power as a function of the waveguide length L for as-grown, once-annealed (600 °C), and twice-annealed (600 °C and 700 °C) samples. Each trace was fitted with the exponential decay function $\exp(-L/L_{\rm SPP})$ and normalized by the value at L=0. Here, the propagation length L_{SPP} was evaluated to be 9.0 ± 0.3 mm, 12.0 ± 0.4 mm, and 14.7 ± 0.7 mm for the as-grown, onceannealed, and twice-annealed samples, respectively. In this way, the SPP propagation length was shown to increase noticeably by the thermal annealing treatment.



Total Pages: 7

FIG. 3. Semi-logarithmic plot of normalized output power as a function of the SPP waveguide length L for the as-grown (squares), once-annealed (triangles), and twice-annealed (circles) samples. Exponential decay curves fitted to these data are also shown as solid lines. The propagation length of SPP was evaluated from each trace to be 9.0 ± 0.3 mm, 12.0 ± 0.4 mm, and 14.7 ± 0.7 mm.

Figure 4 shows an AFM topography image (upper pan- 210 els) of the waveguide surface and the corresponding cross- 211 sectional height data (lower panels) for (a) as-grown, (b) 212 once-annealed (600 °C), and (c) twice-annealed (600 °C and 213 700 °C) samples. Here, the sectional surface is indicated as 214 dashed lines in the topography images. It is evident from the 215 cross-sectional height data that surface roughness was sup- 216 pressed by the annealing treatment. By calculating root mean 217 squares of deviations in height data, the surface roughness is 218 estimated to be 5.7 nm, 2.8 nm, and 2.2 nm for the as-grown, 219 once-annealed, and twice-annealed samples, respectively. 220 The granular pattern typical for polycrystalline gold was 221 clearly observed for the as-grown sample, as shown in Fig. 222 4(a). Here, we estimated the average diameter of crystallite 223 grains to be $70 \pm 20 \,\mathrm{nm}$ for the as-grown sample, by analyz- 224 ing the height data with the watershed algorithm²⁶ while 225 assuming spherical shape for each grain. In contrast, grain 226 boundaries were not identified for the annealed samples. We 227 therefore proceeded to observe waveguide surface with SEM 228 and EBSD.

Figure 4(d) shows a SEM image for the twice-annealed 230 sample. It does not identify grain boundaries nor does the 231 AFM topographic image shown in Fig. 4(c). Figure 4(e) 232 shows the pattern quality map, constructed from the EBSD 233 data, for the same sample and for the same area as shown in 234 Fig. 4(d). Here, every point is assigned a brightness based on 235 the EBSD pattern quality for that point. Bright area has high 236 pattern quality (i.e., the measured electron diffraction pattern 237 matches well with the ideal diffraction pattern of crystalline 238 gold) and indicates crystalline gold. Dark area, in contrast, 239 has low pattern quality and indicates grain boundaries, dislo- 240 cations, and voids. The corresponding inverse pole figure 241 (normal direction) is shown in Fig. 4(f) for reference. In this 242 way, the granular pattern is successfully identified by the 243 EBSD measurement. By analyzing the pattern quality data 244 with the watershed algorithm, ²⁶ while assuming spherical ²⁴⁵ shape for each grain, we estimated the average diameter of 246

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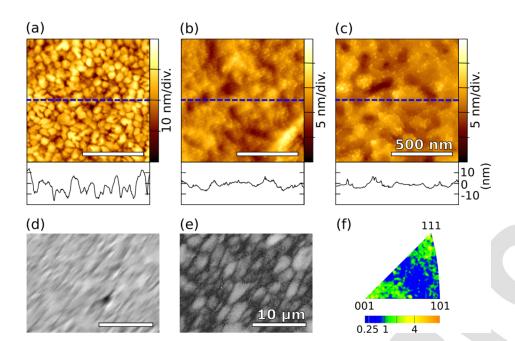


FIG. 4. AFM topography images (upper panels) of the waveguide surface and the corresponding cross-sectional height data (lower panels) for (a) as-grown, (b) once-annealed (600 °C), and (c) twiceannealed (600 °C and 700 °C) samples. The sectional surface is indicated as dashed lines. A SEM image, an EBSD pattern quality map, and an inverse pole figure for the twice-annealed sample are shown in (d), (e), and (f), respectively.

crystallite grains to be as large as $2 \pm 1 \mu m$. In this way, thermal annealing at 700 °C or below was found to significantly increase the grain size and reduce the surface roughness.

The SPP-light coupling efficiency of the coupler was estimated to be 0.18 from our experiments. Although the optimum incident angle for the maximum coupling efficiency shifted by $\sim 0.5^{\circ}$ upon annealing, the change in the maximum coupling efficiency was not observed. Additional AFM measurements confirmed that the coupler gratings had ideal rectangular profiles before and after the thermal annealing. This behavior is in contrast to the observation by Cleary et al.²³ that rectangular profiles of silver gratings became more sinusoidal after annealing. Such contrast may be caused by that their annealing temperature was closer to the melting point, compared with our case. Note that their annealing temperature of 840 °C was only about 122 °C lower than the melting point of silver (962 °C). In our case, the annealing temperature of 700 °C was about 364 °C lower than the melting point of gold (1064 °C).

V. DISCUSSIONS

In the following, we discuss the physics behind the elongation of the SPP propagation length upon thermal annealing, based on our observations of increased grain size (from 70 nm to 2000 nm) and suppressed surface roughness (from $5.7 \, \text{nm} \text{ to } 2.2 \, \text{nm}$).

Based on the Drude model, the complex dielectric constant of gold at frequency ω is expressed as

$$\tilde{\epsilon}(\omega) \equiv \epsilon' + i\epsilon'' = \epsilon_{\infty} - \frac{\omega_p^2}{\omega^2 + i\omega\omega_{\tau}}
= \epsilon_{\infty} - \frac{\omega_p^2}{\omega^2 + \omega_{\tau}^2} + i\frac{\omega_p^2\omega_{\tau}}{\omega(\omega^2 + \omega_{\tau}^2)},$$
(2)

where ϵ' and ϵ'' are the real and imaginary parts of the dielec-275 tric constant of gold, respectively, ϵ_{∞} is the dielectric background, $\omega_p = \sqrt{Ne^2/(\epsilon_0 m^*)}$ is the plasma frequency, N is the free electron density, e is the elementary charge, ϵ_0 is the 277 permittivity of vacuum, m^* is the effective mass of the elec- 278 tron, $\omega_{\tau} = 1/\tau$ is the electron scattering rate, and τ is the 279 electron scattering time. 280

Considering only non-radiative losses, the SPP propaga- 281 tion length $L_{\rm SPP}$ at the gold/air interface is expressed as 282

$$L_{\rm SPP} = \frac{1}{2\,{\rm Im}[k_{\rm SPP}]},\tag{3}$$

where $k_{\rm SPP} = (\omega/c) \sqrt{\tilde{\epsilon}/(\tilde{\epsilon}+1)}$ is the complex wavenumber 283 of SPP and c is the speed of light in vacuum. By substituting 284 the dielectric constant of polycrystalline gold²⁷ into Eq. (3), ²⁸⁵ $L_{\rm SPP}$ is calculated to be 12.3 mm at a wavelength of 10.6 μ m. 286 Our experimentally measured values of $9.0 \pm 0.3 \,\mathrm{mm}$, 287 12.0 ± 0.4 mm, and 14.7 ± 0.7 mm agree with this theoreti- 288 cal estimation, confirming that mid-IR SPPs at the gold/air 289 interface propagate for a distance about or above 10 mm. 290 This agreement suggests that non-radiative losses have major 291 contribution to the observed attenuation behavior. 292

Assuming $\epsilon'' < |\epsilon'|$ and $|\epsilon'| \gg 1$, both of which are valid 293 for $\omega_{\tau} < \omega \ll \omega_{p}$, Eq. (3) is approximated as²⁸ 294

$$L_{\rm SPP} \simeq \frac{c}{\omega} \left(\frac{\epsilon' + 1}{\epsilon'} \right)^{3/2} \frac{\epsilon'^2}{\epsilon''} \simeq \frac{c}{\omega} \frac{\epsilon'^2}{\epsilon''}. \tag{4}$$

Here, we note that our operating frequency $\omega \sim 1/5.6\,\mathrm{fs}^{-1}$, 295 corresponding to 943 cm⁻¹ in wavenumber, satisfies the condition $\omega_{\tau} < \omega \ll \omega_p$, according to the spectroscopic ellipsometry measurements on evaporated gold^{20,21} (e.g., the scattering 298 rate ω_{τ} is $<1/14 \,\mathrm{fs}^{-1}$, or $<380 \,\mathrm{cm}^{-1}$, for grain size of 299 >56 nm,²¹ and the plasma frequency ω_p exists in the ultravio- 300 let region). Equation (4) describes how $L_{\rm SPP}$ depends on ϵ' and 301 ϵ'' , and therefore on the Drude parameters of ω_{τ} , ϵ_{∞} , and ω_{p} .

Trollmann and Pucci²¹ have evaluated the Drude parame- 303 ters for evaporated gold films of varied morphology. They 304 have shown that the electron scattering rate ω_{τ} increases with 305 decreasing grain size, and that such dependence becomes 306

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even stronger when the grain size is smaller than their estimated bulk electron mean free path of ${\sim}56\,\mathrm{nm}$. Here, we note that their estimated value is compatible with the value 35.9 nm measured for single crystalline gold by Canchal-Arias and Dawson²⁹ According to the results of Trollmann and Pucci,²¹ the electron scattering rate of our twice-annealed sample (the grain size of 2000 nm) is about 1.5 times smaller than that of our as-grown sample (the grain size of 70 nm). Now, it is reasonable to interpret our results as that thermal annealing induced the grain-size enlargement, and the accompanying lowering of ω_{τ} .

A lowering in ω_{τ} should result in the elongation of L_{SPP} , as explained in the following. From Eqs. (2) and (4), we obtain:

$$\frac{dL_{\text{SPP}}}{d\omega_{\tau}} \simeq \frac{c}{\omega} \frac{\epsilon'}{\epsilon''^2} \left(2 \frac{d\epsilon'}{d\omega_{\tau}} \epsilon'' - \epsilon' \frac{d\epsilon''}{d\omega_{\tau}} \right)
\simeq \frac{c}{\omega^2} \frac{\epsilon'}{\epsilon''^2} \frac{\omega_p^4 (\omega^2 + 3\omega_{\tau}^2)}{(\omega^2 + \omega_{\tau}^2)^3}, \tag{5}$$

where $\epsilon' \simeq -\omega_p^2/(\omega^2 + \omega_\tau^2)$ is used to derive the final expression. Since $\epsilon' < 0$ holds at our operating frequency ω , we obtain $dL_{\rm SPP}/d\omega_{\tau} < 0$. There are two kinds of physics behind the behavior that L_{SPP} monotonically elongates with decreasing ω_{τ} . One is the suppression in local Joule heating efficiency, expressed as a decrease in ϵ'' . The other is that increased portion of the electromagnetic field exists in air (outside gold), which suppresses the total Ohmic losses.

For quantitative understanding of SPP attenuation in visible range, Kuttge et al. 12 studied additional loss mechanism, namely, scattering of SPPs at grain boundaries, by measuring both the propagation length and the dielectric function. Lee et al.³⁰ showed the existence of electromagnetic hotspots on copper films owing to multiple SPP reflection within the hotspots or cavity effect, and associated them with triple junctions, where three grain boundaries intersect on the surface, and large and deep boundary grooves. Our observation of elongated L_{SPP} with enlarged grain size is in line with their conclusions that grain boundaries induce SPP attenuation.

Suppressed surface roughness may also lead to elongated L_{SPP} by reducing the scattering of SPPs. This contribution, however, would be negligible in our observed elongation of L_{SPP} , since attenuation due to SPP scattering by surface roughness of <10 nm is estimated to be by many orders of magnitude smaller than the attenuation for the propagation length of ~ 10 mm. 12,19,31

Based on the discussions above, we attribute the elongation of SPP propagation length to suppressed non-radiative damping (or Ohmic loss) and suppressed SPP scattering, both of which originate from reduction in grain boundaries. Simultaneous measurements on dielectric constants would enable us to distinguish one contribution from another.

We lastly comment on the phenomena induced by the thermal annealing. Observed enlargement of the grain size is understood as a result that smaller crystallite grains preferentially melt upon annealing³² and re-crystallize into larger particles. During such phenomena, each crystallite grain can be connected with each other by the necking formation,

which would suppress the surface roughness and make grain 359 boundaries invisible with AFM. The minor side effect of 360 annealing was the formation of pinholes with diameters on 361 the order of 100 nm at the metal surface. They appeared with 362 a number density of $0.16 \,\mu\text{m}^{-2}$ after the first annealing and 363 with a number density of $0.44 \, \mu \text{m}^{-2}$ after the second annealing. Such pinholes are much smaller than the SPP wave- 365 length but may have induced scattering of SPPs and reduced 366 the net elongation of L_{SPP} .

VI. CONCLUSIONS

We demonstrated that SPPs at the gold/air interface 369 propagate for a distance about or above 10 mm at a wave- 370 length of $10.6 \,\mu\text{m}$. The measured propagation length is in 371 good agreement with the value predicted from the dielectric 372 constant of polycrystalline gold. We also successfully dem- 373 onstrated that the SPP propagation length can be increased 374 by the simple treatment of thermal annealing accompanied 375 by the increased grain size and decreased surface roughness. 376 We attributed the elongated propagation length to suppressed 377 non-radiative damping (or Ohmic loss) and suppressed SPP 378 scattering, both of which originate from reduction in grain 379 boundaries. Quantitative evaluation of the SPP propagation 380 length, correlated with material's morphology, is important 381 in designing plasmonic devices and beneficial for deeper 382 understandings of the mechanism of the losses that underlie 383 electric-field enhancement achievable upon SP excitations.

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```
<sup>1</sup>R. Stanley, Nat. Photonics 6, 409 (2012).
```

⁹F. Kusa, K. E. Echternkamp, G. Herink, C. Ropers, and S. Ashihara, AIP Adv. 5, 077138 (2015).

¹⁰F. Kusa and S. Ashihara, J. Appl. Phys. **116**, 153103 (2014).

¹¹A. V. Zayats, Nature **495**, S7 (2013).

¹²M. Kuttge, E. J. R. Vesseur, J. Verhoeven, H. J. Lezec, H. A. Atwater, and 416 A. Polman, Appl. Phys. Lett. 93, 113110 (2008). 417

²S. Law, V. Podolskiy, and D. Wasserman, Nanophotonics **2**, 103 (2013).

³F. Neubrech, A. Pucci, T. W. Cornelius, S. Karim, A. García-Etxarri, and J. Aizpurua, Phys. Rev. Lett. 101, 157403 (2008).

⁴C. V. Hoang, M. Oyama, O. Saito, M. Aono, and T. Nagao, Sci. Rep. 3, 1175 (2013).

⁵J. Cleary, R. Peale, D. Shelton, G. Boreman, R. Soref, and W. Buchwald, MRS Proc. 1133, AA10-03 (2011). 2008

⁶F. Kusunoki, J. Takahara, and I. Kobayashi, Electron. Lett. **39**, 23 (2003). ⁷T. W. Ebbesen, C. Genet, and S. I. Bozhevolnyi, Phys. Today **61**(5), 44

⁸R. Soref, R. E. Peale, and W. Buchwald, Opt. Express 16, 6507 (2008).

J_ID: JAPIAU DOI: 10.1063/1.4966934 Date: 31-October-16 Stage: Page: 6 Total Pages: 7

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J. Appl. Phys. **120**, 000000 (2016)

418	¹³ R. E. Peale, O. Lopatiuk, J. Cleary, S. Santos, J. Henderson, D. Clark, L.	²³ J. W. Cleary, G. Medhi, R. E. Peale, and W. R. Buchwald, Appl. Opt. 49,	43
419	Chernyak, T. A. Winningham, E. D. Barco, H. Heinrich, and W. R.	3102 (2010).	43
420	Buchwald, J. Opt. Soc. Am. B 25, 1708 (2008).	²⁴ M. G. Moharam and T. K. Gaylord, J. Opt. Soc. Am. 71 , 811 (1981).	43
421	¹⁴ H. U. Yang, J. D'Archangel, M. L. Sundheimer, E. Tucker, G. D.	²⁵ C. Nogues and M. Wanunu, Surf. Sci. 573 , L383 (2004).	43
422	Boreman, and M. B. Raschke, Phys. Rev. B 91, 235137 (2015).	²⁶ P. Klapetek, I. Ohlídal, A. Montaigne-Ramil, A. Bonanni, D. Stifter, and	43
423	¹⁵ J. McMullen, Solid State Commun. 17 , 331 (1975).		43
424	¹⁶ Z. Schlesinger and A. Sievers, Solid State Commun. 43, 671 (1982).	²⁷ E. D. Palik, <i>Handbook of Optical Constants of Solids</i> (Academic Press,	43
425	¹⁷ Z. Schlesinger and A. J. Sievers, Phys. Rev. B 26 , 6444 (1982).	2002).	44
426	¹⁸ J. Schoenwald, E. Burstein, and J. Elson, Solid State Commun. 12 , 185 (1973).	²⁸ H. Raether, Surface Plasmons on Smooth and Rough Surfaces and on	44
427	¹⁹ H. Shiba, M. Haraguchi, and M. Fukui, J. Phys. Soc. Jpn. 63 , 1400 (1994).		44
428	²⁰ R. L. Olmon, B. Slovick, T. W. Johnson, D. Shelton, SH. Oh, G. D.	²⁹ D. Canchal-Arias and P. Dawson, Surf. Sci. 577 , 95 (2005).	44
429	Boreman, and M. B. Raschke, Phys. Rev. B 86, 235147 (2012).	³⁰ H. S. Lee, C. Awada, S. Boutami, F. Charra, L. Douillard, and R. E. de	44
430	²¹ J. Trollmann and A. Pucci, J. Phys. Chem. C 118 , 15011 (2014).	Lamaestre, Opt. Express 20 8974 (2012).	44
431	²² S. T. Koev, A. Agrawal, H. J. Lezec, and V. A. Aksyuk, Plasmonics 7, 269	³¹ D. L. Mills, Phys. Rev. B 12 , 4036 (1975).	44
432	(2012).	³² P. Buffat and JP. Borel, Phys. Rev. A 13 , 2287 (1976).	44

D. Franta,